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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Shigeomi Chono, et al.

Attorney Docket No.: YMUCP002

Application No.: 10/814,110

Examiner: D.T. Nguyen

Filed: March 30, 2004

Group: 2871

Title: LIQUID CRYSTAL FLOW FORMING  
MECHANISM, METHOD OF FORMING SAME,  
AND OBJECT MOVING MECHANISM USING  
LIQUID CRYSTAL FLOW

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Alexandria, Virginia 22313-1450 on January 5, 2006.

Signed: 

Deborah Neill

**INFORMATION DISCLOSURE STATEMENT**

**37 CFR §§1.56 AND 1.97(b)**

Commissioner for Patents  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. YMUCP002).

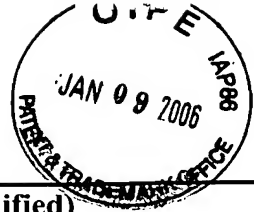
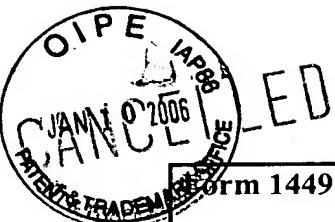
Respectfully submitted,

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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	<b>YMUCP002</b>	<b>10/814,110</b>
	Applicant:	
	<b>Shigeomi Chono, et al.</b>	
	Filing Date	Group
	<b>March 30, 2004</b>	<b>2871</b>

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A						
	B						
	C						

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	D	2001-260100	25/09/01	Japan			X	
	E	2001-013895	19/01/01	Japan			X	
	F	06-046584	18/02/94	Japan			X	
	G	11-230023	24/08/99	Japan			X	
	H	08-270615	15/10/96	Japan			X	
	I	3005263	10/05/94	Japan			X	

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	J	PCT/JP02/10129, English translation of Japanese examiner's comments.
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.